

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application

Inventor(s): Tue Nguyen, Tai Dung Nguyen

Appln. No.: 09/898,439

Appeal No.: 2009-1022

Conf. No.: 1885

Filed: July 5, 2001

Title: PLASMA SEMICONDUCTOR  
PROCESSING SYSTEM AND METHOD

**PATENT APPLICATION**

Art Unit: 2892

Examiner: Quoc Dinh Hoang

Atty. Docket No.: TEGL-01165US0

**Customer No. 23910**

**REPLY AND AMENDMENT UNDER 37 C.F.R. 1.114**

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This Reply and Amendment is in response to the final Office Action dated December 18, 2006, and the subsequent DECISION ON APPEAL entered by the Board of Patent Appeals and Interferences on July 20, 2009. Applicants hereby submit a Request for Continued Examination (RCE) under 37 CFR 1.114.

Please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.